

MNL 228 201827

SS 1?

FILE JAPIO;J61073071/PN

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COVERS PATENT APPLICATIONS FROM OCT 1976 THRU NOV 1993 (9406)

SS 1 RESULT (1)

SS 2?

PRT FU

-1- (JAPIO)

AN - 86-073071

TI - FLEXIBLE HINGE DEVICE

PA - (2000708) INTERNATL STANDARD ELECTRIC CORP

IN - JIYON, KURISUTOFUAA GURIINUTSUDO; DEIBUIDO, UIRUSON

PN - 86.04.15 J61073071, JP 61-73071

AP - 84.09.14 84JP-191876, 59-191876

IC - G01P-015/125

JC - 46.1 (INSTRUMENTATION--Measurement)

SS 2?

J62207917/PN

SS 2 RESULT (1)

SS 3?

PRT FU

U R 1

-1- (JAPIO)

AN - 87-207917

TI - VIBRATION AND ACCELERATION SENSOR

PA - (2000522) FUJITSU LTD

IN - ENDO, MICHIO; FUJIWARA, YOSHIAKI; KOJIMA, YUJI

PN - 87.09.12 J62207917, JP 62-207917

AP - 86.03.10 86JP-050531, 61-50531

SO - 88.02.27 SECT. P, SECTION NO. 671; VOL. 12, NO. 66, PG. 142.

IC - G01H-011/06; G01P-015/125

JC - 46.1 (INSTRUMENTATION--Measurement)

AB - PURPOSE: To obtain the titled sensor which can be easily manufactured by a simple constitution, and also, has a high sensitivity and a high accuracy, by forming a cantilever which is bent by receiving an acceleration, to a sandwich structure which has been inserted and held by a conductive metallic thin film and an SiO(sub 2) film.

CONSTITUTION: A minute cantilever 11 which has been formed to a sandwich structure by inserting and holding an Al thin film 12 by SiO(sub 2) films 13, 14 is provided on an Si substrate 10, and also, in a position opposed to the cantilever 11 of the Si substrate 10, a high conductive layer 15 is formed by diffusing an impurity. When the cantilever 11 is bent by receiving an acceleration, a variation of an electric capacity is generated between the conductive metallic thin film 12 of the cantilever 11, and the high conductive layer 15 of the Si substrate 10, therefore, by detecting it, a vibration or an acceleration can be sensed. Also, by forming the conductive layer of the cantilever 11 by the metallic thin film 12, the man-hour for manufacture can be curtailed. Moreover, by providing an FET on the same substrate, the vibration and acceleration can be sensed with a high sensitivity and a high accuracy.

SS 3?
FILE WPAT;J61073071/PN

YOU ARE NOW CONNECTED TO WPAT.

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COVERS 1963 THRU WEEKLY UPDATE 9418/UP, 9418/UPEQ, 9415/UPA, 9408/UPB;
WPI 9417/UPEQ

DERWENT PATENT DRAWINGS NOW AVAILABLE. SEE NEWSDOC N213

TERM (J61073071/PN) NOT FOUND.
SS 1 RESULT (0)

SS 2?
SAVE MNL

SAVE MNL COMPLETED.
SS 2?
BYE

SS 2 RESULT (68)

SS 3?
STOP Y

SESSION FINISHED 06/29/94 2:45 P.M. (CENTRAL TIME)
ELAPSED TIME ON WPAT: 0.01 HRS.
\$2.10 EST COST CONNECT TIME.
\$2.10 EST TOTAL COST THIS WPAT SESSION.

ELAPSED TIME THIS SESSION: 0.06 HRS.
\$8.12 EST COST CONNECT TIME.
\$0.78 EST COST TELECOM.
\$1.30 EST COST ONLINE PRTS: 2
\$9.42 EST TOTAL COST THIS TERMINAL SESSION.